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Group Art Unit: 2823  
Title: Film Forming Method in which Flow Rate

Fig. 1A

SMALL QUANTITY  
 $\text{SiH}_4$  GAS (PIPE 1)

Fig. 1B

LARGE QUANTITY  
 $\text{SiH}_4$  GAS (PIPE 4)

Fig. 1C

Ar GAS (PIPES 3, 6)

Fig. 1D

$\text{O}_2$  GAS (PIPES 2, 5)

Fig. 1E

HIGH FREQUENCY POWER 19

